

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Atsushi TAKAKUWA et al.

Application No.: New U.S. Application

Filed: January 14, 2004

Docket No.: 118336

For: DEVICE MANUFACTURING METHOD AND DEVICE, ELECTRO-OPTIC DEVICE,
AND ELECTRONIC EQUIPMENT

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 CFR §1.56, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached PTO-1449. Unless otherwise indicated herein, one copy of each reference is attached. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

- ☒ 1. This Information Disclosure Statement is being filed (a) within three months of the U.S. filing date of this non-CPA application, OR (b) before the mailing date of a first Office Action on the merits in the present application. No certification or fee is required.
- ☒ 2. Relevance of references 1 and 11-12 is discussed in the present specification.
- ☒ 3. The present application was filed or entered the U.S. National Stage of the PCT after June 30, 2003. In accordance with the June 11, 2003, Notice waiving the requirements of 37 C.F.R. §1.98(a)(2)(i), copies of any U.S. patents and patent application publications are not attached.
- ☒ 4. English-language Abstracts of the non-English language references 2-12 are attached hereto.

- ☒ 5. A computer-generated English translation of the following Japanese Patent Publication has been obtained from the website of the Japanese Patent Office (<http://www.jpo.go.jp>), and is attached, but has not been reviewed for accuracy. See References 2-12.

Respectfully submitted,



James A. Oliff
Registration No. 27,075

Thomas J. Pardini
Registration No. 30,411

JAO:TJP/mlo

Date: January 14, 2004

OLIFF & BERRIDGE, PLC
P.O. Box 19928
Alexandria, Virginia 22320
Telephone: (703) 836-6400

<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
--

Form PTO-1449 (REV. 8-83)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118336		APPLICATION NO. New U.S. Application	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)				APPLICANT(S) Atsushi TAKAKUWA et al.			
				FILING DATE January 14, 2004		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	
	1.	6,057,067	5/2/2000	ISBERG et al.			
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	
	2.	JP A 2003-31778 w/abstract & transl.	1/31/2003	JAPAN			
	3.	JP A 2003-142666 w/abstract & transl.	5/16/2003	JAPAN			
	4.	JP A 2000-133809 w/abstract & transl.	5/12/2000	JAPAN			
	5.	JP A 2001-51296 w/abstract & transl.	2/23/2001	JAPAN			
	6.	JP A 2001-125138 w/abstract & transl.	5/11/2001	JAPAN			
	7.	JP A 2002-217390 w/abstract & transl.	8/2/2002	JAPAN			
	8.	JP A 2002-217391 w/abstract & transl.	8/2/2002	JAPAN			
	9.	JP A 10-125929 w/abstract & transl.	5/15/1998	JAPAN			
	10.	JP A 10-125930 w/abstract & transl.	5/15/1998	JAPAN			
	11.	JP A 10-125931 w/abstract & transl.	5/15/1998	JAPAN			
	12.	JP A 11-26733 w/abstract & transl.	1/29/1999	JAPAN			
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
	13.	Tatsuya Shimoda et al.; "Surface Free Technology by Laser Annealing (SUFTLA)"; IEDM; 1999; pp 289-292					

Date: January 14, 2004

	14.	Sumio UTSUNOMIYA et al.; "Low-Temperature poly-Si TFT transferred onto plastic substrates by using surface free technology by laser ablation/annealing (SUFTLA); Journal of the SID; 2002; pp 69-73
	15.	S. Utsunomiya et al.; "Low Temperature Poly-Si TFT-LCD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA); Asia Display/IDW; 2001; pp 339-342
	16.	Sumio Utsunomiya et al.; "4-3: Flexible TFT-LEPD Transferred onto Plastic Substrate Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA)"; EURODISPLAY; 2002; pp 79-82
	17.	Akihiko ASANO et al.; "43.2: Low-Temperature Polycrystalline-Silicon TFT Color LCD Panel Made of Plastic Substrates"; SID 02 DIGEST; 2002; pp 1196-1199
	18.	M. Kimura et al.; "An area-ratio gray-scale method to achieve image uniformity in TFT-LEPDs"; Journal of SID; 2000; pp 93-97
	19.	T. Shimoda et al.; " Technology for Active Matrix Light Emitting Polymer Displays"; IEDM; 1999; pp 107-110
	20	Sumio Utsunomiya et al.; "21.3: Flexible Color AM-OLED Display Fabricated Using Surface Free Technology by Laser Ablation/Annealing (SUFTLA) and Ink-jet Printing Technology" SID 03 DIGEST; 2003; pp 864-867
EXAMINER		DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.		

Date: January 14, 2004